



PATENT APPLICATION
ATTORNEY DOCKET NO. LMRX-P032/P1205

**IN THE
UNITED STATES PATENT & TRADEMARK OFFICE**

Applicant: Kim et al

Application No. 10/804,430

Examiner: Norton, Nadine Georgianna

Filed: 3/19/2004

Group No. 1763

**Title: METHODS FOR THE
OPTIMIZATION OF SUBSTRATE
ETCHING IN A PLASMA PROCESSING
SYSTEM**

Confirmation No. 7228

Certificate of Mailing

I hereby certify that this correspondence is being deposited with the US Postal Service as First Class Mail in a postage-paid envelope addressed to the Commissioner for Patents, PO BOX 1450, Alexandria, VA 22313-1450, on August 24, 2005.

Signed: /Cassandra Reynolds/

Cassandra Reynolds

PRELIMINARY AMENDMENT

Sir:

Please amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Abstract begin on page 4 of this paper.

Amendments to the Claims begin on page 5 of this paper.

Amendments to the drawings begin on page 10 of this paper.

Remarks/Arguments begin on page 11 of this paper.